



1752  
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Docket No. AM5230

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

ANISUL KHAN et al

Serial No.: 09/866,313

Filed: May 24, 2001

Group Art Unit: 1752

RECEIVED  
APR 15 2002  
TC 1700

For: METHOD OF ELIMINATING NOTCHING  
WHEN ANISOTROPICALLY ETCHING  
SMALL LINEWIDTH OPENINGS IN  
SILICON ON INSULATOR

INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.56

To: Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

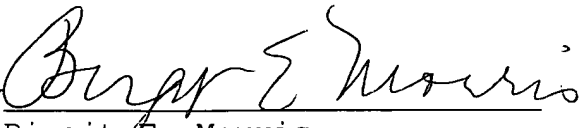
The following reference is submitted for the Examiner's  
convenience.

US Patent 5,501,893 to Laermer et al.

A copy of the reference is attached. Applicants request that  
this reference be made part of the application file.

Respectfully submitted,

ANISUL KHAN et al

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The undersigned declares that this correspondence  
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